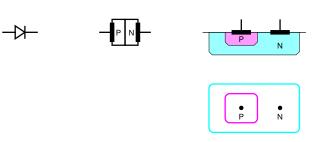
Components for IC Design

Diodes and Bipolar Transistors

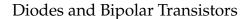
Diode



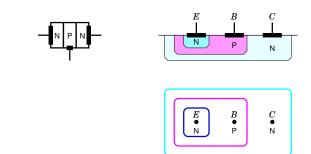
- Ideal structure 1D
- Real structure 3D
- Depth controlled implants.

3001

Components for IC Design



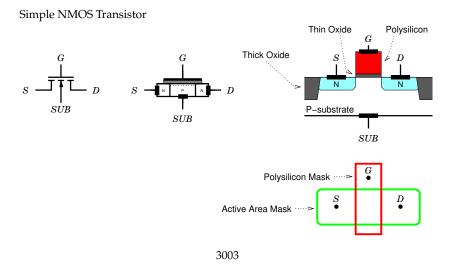
NPN Transistor



• Two n-type implants.

Components for IC Design



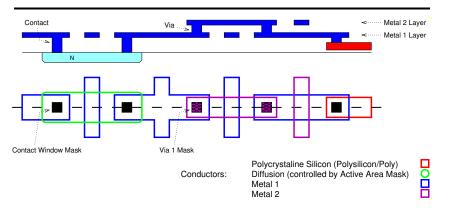


Components for IC Design



- Active Area mask defines extent of *Thick Oxide*.
- Polysilicon mask also controls extent of *Thin Oxide* (alias *Gate Oxide*).
- N-type implant has no extra mask.
- It is blocked by thick oxide and by polysilicon.
- The implant is *Self Aligned*.
- Substrate connection is to bottom of wafer.
- All substrates to ground.
- Gate connection not above transistor area.
- Design Rule.

Interconnect

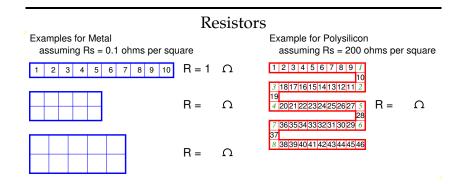


- Crossing conductors on different masks do not interact¹.
- Explicit contact/via is required for connection.
- Crossing conductors on the same mask are always connected.

¹the exception to this rule is that polysilicon crossing diffusion gives us a transistor

3005

Components for IC Design

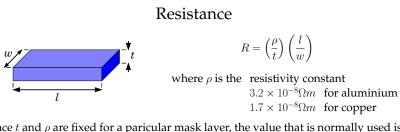


- for larger resistances we need minimum width poly (often combined with a *serpantine* shape) to save on area
- corner squares count as half² squares
- for predicatability and matching we may need wider tracks without corners

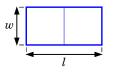
²effective resistance $\approx 0.56 R_s$

3007

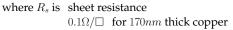
Interconnect



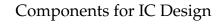
Since *t* and ρ are fixed for a particular mask layer, the value that is normally used is the sheet resistance: $R_s = \begin{pmatrix} \rho \\ t \end{pmatrix}$.

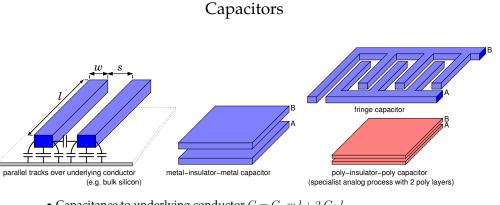


 $R = R_s\left(\frac{l}{w}\right)$



 R_s = resistance of a square (i.e. w = l) so the units for R_s are Ω/\Box (ohms per square).





- Capacitance to underlying conductor $C = C_a w l + 2 C_f l$
- Coupling capacitance to adjacent track $C = C_c l/s$ where $C_{ar} C_f$, C_c are constants for a given layer and process

in digital designs our only aim is to minimise parasitic capacitance